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(54) Title: PROCESS TANK TEMPERATURE-MEASURING DEVICE AND SUBSTRATE PROCESSING APPARATUS

(54) 发明名称: 工艺槽测温装置及基板处理设备

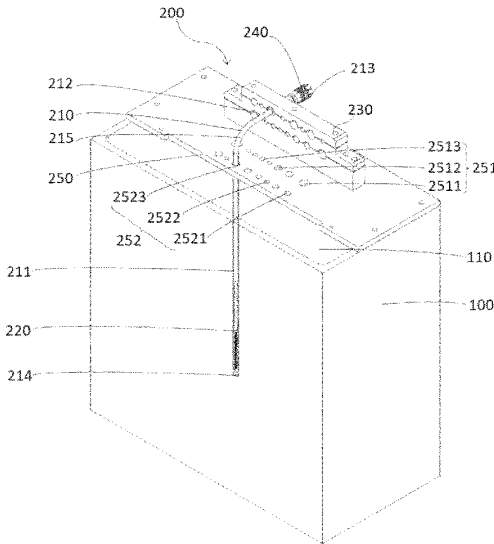


图 1

(57) Abstract: Disclosed in the present invention are a process tank temperature-measuring device and a substrate processing apparatus. The process tank temperature-measuring device is configured to detect the temperature of a chemical liquid in a process tank, and a process tank opening is provided at the upper end of the process tank. The process tank temperature-measuring device comprises: a protective tube, comprising a temperature-measuring part and an extending part, which are connected in sequence and are in conduction with each other, wherein one end of the temperature-measuring part away from the extending part is sealed to form the bottom of the protective tube, one end of the extending part away from the temperature-measuring part is open to form an inlet of the protective tube, and a preset included angle is formed between the temperature-measuring part and the extending part in an axial direction; and a temperature-measuring probe, which is installed inside the temperature-measuring part and located at the bottom of the protective tube. The bottom of the protective tube is configured to be immersed in the chemical liquid of the process tank, such that the temperature-measuring probe detects the temperature of the chemical liquid in the process tank. Moreover, the inlet of the protective tube is formed directly above the opening

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of the process tank, thereby achieving the effects of a simple structure and high corrosion resistance of the process tank temperature-measuring device.

(57) 摘要: 本发明公开了一种工艺槽测温装置及基板处理设备, 该工艺槽测温装置用于检测工艺槽内的化学液温度, 工艺槽上端具有工艺槽开口。该工艺槽测温装置包括: 防护管, 包括依次连接且相互导通的测温部和延伸部, 测温部远离延伸部的一端密封形成防护管底部, 延伸部远离测温部的一端开口形成防护管入口, 且测温部和延伸部轴向具有预设夹角; 测温探头, 装设于测温部的内部, 且位于防护管底部。其中, 防护管底部配置为浸没在工艺槽的化学液中, 以使测温探头检测工艺槽的化学液温度, 且防护管入口配置到工艺槽开口正上方之外, 进而实现了该工艺槽测温装置结构简单、耐腐蚀性强的效果。